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**INFORMATION DISCLOSURE STATEMENT
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Applicant: GUI et al.

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Examiner: P. KIM

Group Art Unit: 2851

Date: July 7, 2005

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U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR					
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					
	IR					
	JR					
	KR					
	LR					
	MR					

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		Abstract		Readily Available	
							Enclosed	No	Enclose	No
	NR									
	OR									
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									
	VR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

OK	WR	Coulon, D., "Application Specific Lithography for MEMS," PowerPoint Presentation, Ultratech Stepper, January 31, 2003, 19 pages.			
PK	XR	Ultratech Inc.: Key Developments, Fifty Collected Press Releases for Ultratech, Inc., dated from July 11, 2000 through June 13, 2005, located at http://news.moneycentral.msn.com/ticker/sigdey.asp?Symbol=US:UTEK , pages 1-8.			
	YR				
	ZR				
	AAR				

Examiner

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Date Considered:

8/18/05

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.